



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

: **Confirmation No. 1632**

Norio KIMURA et al.

: Docket No. 2001-0660A

Serial No. 09/864,208

: Group Art Unit 1763

Filed May 25, 2001

: Examiner Jeffrie R. Lund

SUBSTRATE POLISHING APPARATUS AND
SUBSTRATE POLISHING METHOD

: **Mail Stop: RCE**

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a one month extension of time to respond to the communication of May 16, 2005.

The fee of \$120.00 is

(X) submitted herewith.

() to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.

() Small entity status of this application is established by a Small Entity Status Assertion which

() is enclosed.

() has been previously submitted.

Respectfully submitted,

Norio KIMURA et al.

By

Nils E. Pedersen

Registration No.33,145

Attorney for Applicants

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

09/08/2005 SZEWDIE1 00000018 09864208

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September 7, 2005